

ABSTRACT

A suction-and-holding face for a component in a suction nozzle is
5 formed from a semiconductor ceramic so that the suction-and-holding face to be
brought into direct contact with the component in suction and holding has the
characteristics of a semiconductor. Thus, detrimental effects due to static electricity on
the suction nozzle as well as detrimental effects due to electrical conduction between
the suction nozzle and the component can be prevented from occurring.